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| <b>PATENT ASSIGNMENT COVER SHEET</b> |
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| <b>SUBMISSION TYPE:</b>   | NEW ASSIGNMENT                     |
| <b>NATURE OF CONVEYANCE:</b>  | ASSIGNMENT                         |
| <b>CONVEYING PARTY DATA</b>   |                                    |
| <b>Name</b>   | <b>Execution Date</b>              |
| SE GEUN HA  | 07/12/2018                         |
| <b>RECEIVING PARTY DATA</b>   |                                    |
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| <b>Street Address:</b>  | 53 IMSU-RO                         |
| <b>City:</b>  | GUMI-SI GYEONGSANGBUK-DO           |
| <b>State/Country:</b>   | KOREA, REPUBLIC OF                 |
| <b>Postal Code:</b>   | 39386                              |
| <b>PROPERTY NUMBERS Total: 1</b>  |                                    |
| <b>Property Type</b>  | <b>Number</b>                      |
| <b>Application Number:</b>  | 16040401                           |
| <b>CORRESPONDENCE DATA</b>  |                                    |
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| <b>Address Line 1:</b>  | PO BOX 29001                       |
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| <b>ATTORNEY DOCKET NUMBER:</b>  | 159952/PCH/FMO                     |
| <b>NAME OF SUBMITTER:</b>   | FRANCES M. O'BRIEN                 |
| <b>SIGNATURE:</b>   | /Frances M. O'Brien/               |
| <b>DATE SIGNED:</b>   | 07/25/2018                         |
| <b>Total Attachments: 2</b>   |                                    |
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| source=159952_Assignment#page2.tif  |                                    |

INVENTOR'S DECLARATION AND ASSIGNMENT  
FOR PATENT APPLICATION

PATENT

Title of Invention: APPARATUS OF CONTROLLING TEMPERATURE IN WAFER  
CLEANING EQUIPMENT AND METHOD THEREOF  
Docket No.: 159952

INVENTOR'S DECLARATION

As a below named inventor, I hereby declare that:

This declaration is directed to the attached application unless the following is checked:

..... United States Application or PCT International Application Number .....  
filed on .....

The above-identified application was made or authorized to be made by me.

I believe that I am the original inventor or an original joint inventor of a claimed invention in the above-identified application.

I have reviewed and understand the contents of the above-identified application, including the claims.

I acknowledge the duty to disclose information which is material to patentability as defined in 37 C.F.R. § 1.56, including for continuation-in-part applications, material information which became available between the filing date of the prior application and the national or PCT international filing date of the continuation-in-part application.

I acknowledge that any willful false statement made in this declaration is punishable under 18 U.S.C. § 1001 by fine or imprisonment of not more than five (5) years, or both.

ASSIGNMENT

In consideration of good and valuable consideration, the receipt of which is hereby acknowledged, the undersigned,

(1) Se Geun HA

HEREBY SELL(S), ASSIGN(S) AND TRANSFER(S) TO

(2) SK SILTRON CO., LTD.

having a place of business at

(3) 53 Imsu-ro Gumi-si Gyeongsangbuk-do 39386 Republic of Korea

(hereinafter called "ASSIGNEE") the entire right, title and interest in and to any and all improvements which are disclosed in the application for United States Letters Patent entitled

(4) APPARATUS OF CONTROLLING TEMPERATURE IN WAFER CLEANING EQUIPMENT AND METHOD THEREOF

**INVENTOR'S DECLARATION AND ASSIGNMENT  
FOR PATENT APPLICATION**

Docket No.: 159952

which application executed on even date  
herewith or was

(a) executed on (5a): \_\_\_\_\_;  
(b) filed on (5b): July 19, 2018 \_\_\_\_\_;  
Application No.: 16/040,401 \_\_\_\_\_;

(LEWIS ROCA ROTHGERBER CHRISTIE  
LLP, P.O. Box 29001, Glendale, CA 91209-  
9001) is hereby authorized to insert in (b) the  
specified data, when known.

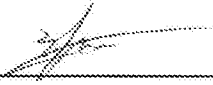
including any and all United States Patents which may be granted on said application, and any and all extensions, divisions, reissues, substitutes, renewals or continuations of said application and patents, and the right to all benefits under all international conventions for the protection of industrial property and applications for said improvements.

It is hereby authorized and requested that the Commissioner of Patents issue any and all of said Letters Patent, when granted, to said ASSIGNEE, its assigns or its successors in interest or its designee.

Upon said consideration, it is further agreed that, when requested, without charge to but at the expense of said ASSIGNEE, the undersigned will execute all divisional, continuing, substitute, renewal, and reissue patent applications; execute all rightful other papers; and generally do everything possible which said ASSIGNEE shall consider desirable for aiding in securing and maintaining patent protection as provided herein.

Se Geun HA  
Legal Name of Inventor

July 12, 2018  
Date

  
Signature

**WITNESSES:**  
\_\_\_\_\_  
\_\_\_\_\_